



Form 1449 (Modified) Information Disclosure Statement By Applicant 1 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
	Applicant:	
	John M. de Larios	
	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A1	3,037,887	06/5/1962	Brenner et al.	134	22
	B1	3,212,762	10/19/1965	Carroll et al.	261	124
	C1	3,436,262	04/1/1969	Crowe et al.	134	10
	D1	3,617,095	11/02/1971	Lissant	406	197
	E1					
	F1	4,085,059	04/18/1978	Smith et al.	134	26
	G1	4,133,773	01/9/1979	Simmons	261	21
	H1	4,156,619	05/29/1979	Griesshammer	134	2
	I1					

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J1	DE-40-38-587	06/11/1992	DE	Fig 1-5	N/A		X
	K1	EP-0827188	03/04/1998	EP	G03F7	42	X	
	L1	EP-0905746	03/31/1999	EP	H01L 21	00	X	
	M1	EP-0989600	03/29/2000	EP	H01L21	465	X	
	N1	JP-2001-064688	03/13/2001	JP	H01L21	304	X	

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O1	AUBERT, JM et al.; "Aqueous foams"; Scientific America; 1986, 74-82, 254
	P1	KITTLE, et al.; "Semiconductor Wafer Cleaning and Drying Using a Foam Medium"; <http://www.aquafoam.com/papers/SCI0202.pdf>; Sematech Novel Wafer Cleans Working Group Meeting, Internet Presentation; 11/13/2001
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form 1449 (Modified) Information Disclosure Statement By Applicant 2 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
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	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A2	4,238,244	12/9/1980	Banks	134	22
	B2	4,781,764	11/1/1988	Leenaars	134	34
	C2	4,817,652	04/4/1989	Liu et al	134	102
	D2					
	E2	4,849,027	07/18/1989	Simmons	134	22
	F2	4,911,761	03/27/1990	McConnell et al.	134	11
	G2	4,962,776	10/16/1990	Liu et al.	134	11
	H2	5,000,795	03/19/1991	Chung et al.	134	37
	I 2	5,048,549	09/17/1991	Hethcoat	134	122R

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J2	JP-02-309638-A	12/25/1990	JP	N/A	N/A	X	
	K2	JP-06-177101	06/24/1994	JP	H01L21	304	X	
	L2	JP-07-006993	01/10/1995	JP	H01L21	304	X	
	M2	EP-11-334874	12/07/1999	EP	B65G	49/07	X	
	N2							

Other Documents

Examiner		
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O2	
	P2	LESTER; "Advanced Wafer-Cleaning Evolution"; < http://www.aquafoam.com/papers/SCI0202.pdf >; Semiconductor International, 25, #2; 2/1/2002
Examiner		Date Considered

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Form 1449 (Modified) Information Disclosure Statement By Applicant 3 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
	Applicant:	
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	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A3	5,102,777	04/07/1992	Lin et al.	430	331
	B3	5,105,556	04/21/1992	Kurokawa et al.	34	12
	C3	5,113,597	05/19/1992	Sylla	34	22
	D3	5,175,124	12/29/1992	Winebarger	437	180
	E3	5,181,985	01/26/1993	Lampert et al.	156	635
	F3	5,226,969	07/13/1992	Watanabe et al.	134	7
	G3	5,242,669	09/7/1993	Flor	423	465
	H3					
	I 3	5,288,332	02/22/1994	Pustilnik et al.	134	27

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J3							
	K3							
	L3							
	M3	JP-2002-66475	03/01/2002	JP	E03C	1/12	X	
	N3	JP-2005-194294	07/21/2005	JP	H01L21	304	X	

Other Documents

Examiner		
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O3	
	P3	
Examiner	Date Considered	

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Form 1449 (Modified) Information Disclosure Statement By Applicant 4 of 15	Attorney Docket No:		U.S.
	LAM2P422		10/608,871
	Applicant:		
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	Filing Date:	Group:	
	June 27, 2003	1746	

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A4	5,306,350	04/26/1994	Hoy et al.	134	22.14
	B4	5,336,371	08/09/1994	Chung et al.	156	659.1
	C4	5,415,191	05/16/1995	Mashimo et al.	134	102.1
	D4	5,417,768	05/23/1995	Smith et al.	134	10
	E4					
	F4	5,472,502	12/05/1995	Batchelder	118	52
	G4	5,494,526	02/27/1996	Paranjpe	134	1
	H4	5,498,293	03/12/1996	Ilardi et al.	134	3
	I 4	5,656,097	08/12/1997	Olesen et al.	134	1

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J4	JP-5-15857	1/5/1993	JP	B08B	1/04	X	
	K4	JP-53-076559	7/7/1978	JP	B08B	3/00	X	
	L4	JP-56-084618	7/10/1981	JP	B01D	53/34	X	
	M4	JP-56-084619	7/10/1981	JP	B01D	53/34	X	
	N4	JP-59-24849	2/08/1984	JP	205	704	X	

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O4	KITTLE, et al.; "Photoreisist Removal Using Aqueous Foam"; Internet; http://www.aquafoam.com/paper/SCCPresentation.pdf
	P4	KITTLE, et al.; "Aqueous Foam Drying and Cleaning of Semiconductor Wafers"; Internet; http://www.aquafoam.com/paper/SCCPresentation.pdf
	Q4	KITTLE, et al.; "Foam Wafer Cleaning - Experimental Proof of Concept"; Internet; http://www.aquafoam.com/paper/Removalall.pdf
	R4	KITTLE, et al.; "Particulate Removal Using a Foam Medium"; Internet; http://www.aquafoam.com/paper/particulate.pdf
	S4	KITTLE, et al. "Removing Particles with a Foam Medium" Internet http://www.aquafoam.com/paper/A2C2foamedium.pdf
Examiner		Date Considered

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Form 1449 (Modified) Information Disclosure Statement By Applicant 5 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
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	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A5	5,660,642	08/26/1997	Brittén	134	30
	B5					
	C5	5,800,626	09/01/1998	Cohen et al.	134	1.3
	D5					
	E5					
	F5	5,904,156	05/18/1999	Advocate, Jr. et al.	134	2
	G5	5,908,509	06/01/1999	Olesen et al.	134	1.3
	H5	5,911,837	06/15/1999	Matthews	134	2
	I 5	5,932,493	08/3/1999	Akatsu et al.	438	745

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J5	JP-60-005529	1/12/1985	JP	H01L	21/304	X	
	K5	JP-62-119543	5/30/1987	JP	H01L	21/304		X
	L5	JP-63-077510	4/7/1988	JP	B01D	36/00	X	
	M5							
	N5							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O5	KITTLE, et al.; "Photoresist Residue Removal Using Aqueous Foam Proof of Concept Experiments"; Internet; http://www.aquafoam.com/paper/Proof-11MB.pdf ; <papers/A2C2photoresist.pdf>; 13-17; 5/1/2002
	P5	LIDE; "Air Composition"; CRC handbook of Chemistry and Physics; 1997;
	Q	
Examiner		Date Considered

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Form 1449 (Modified) Information Disclosure Statement By Applicant 6 of 15	Attorney Docket No:		U.S.
	LAM2P422		10/608,871
	Applicant:		
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	June 27, 2003	1746	

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A6	5,944,581	08/31/1999	Goenka	431	39
	B6	5,944,582	08/31/1999	Talieh	451	41
	C6					
	D6	5,951,779	09/14/1999	Koyanagi et al.	134	2
	E6	5,964,954	10/12/1999	Matsukawa et al.	134	6
	F6	5,964,958	10/12/1999	Ferrell et al.	134	26
	G6	5,968,285	10/19/1999	Ferrell et al.	134	26
	H6					
	I 6	6,048,409	04/11/2000	Kanno et al.	134	34

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J6	WO-00/59006	10/5/2000	WIPO	H01L	21/00	X	
	K6	WO-01/12384	2/22/2001	WIPO	B24B	37/00	X	
	L6	WO-02/101795	12/19/2002	WIPO	H01L	21/00	X	
	M6	WO-2000/33980	6/15/2000	WIPO	B08B	3/00	X	
	N6	WO-2005/006424	1/20/2005	WIPO	H01L	21/306	X	

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O6	
	P6	
	P6	
Examiner		Date Considered

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Form 1449 (Modified) Information Disclosure Statement By Applicant 7 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
	Applicant:	
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	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A7	6,049,996	04/18/2000	Freeman et al.	34	362
	B7	6,081,650	06/27/2000	Lyons et al	386	95
	C7	6,090,217	07/18/2000	Kittle	134	11
	D7	6,092,538	07/25/2000	Arai et al.	134	1.3
	E7	6,152,805	11/28/2000	Takahashi	451	36
	F7	6,158,445	12/12/2000	Olesen et al.	134	1.3
	G7	6,167,583	01/02/2001	Miyashita et al.	15	77
	H7	6,228,563	05/08/2001	Starove et al.	430	327
	I7					

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J7	WO 2005/064647	7/14/2005	WIPO	H01L	21/00	X	
	K7	WO-99/16109	4/1/1999	WIPO	H01L	21/00	X	
	L7	JP 2003-282513	10/03/2003	JP	H01L	21/304	X	
	M7							
	N7							

Other Documents

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	O7	
	P7	
	P7	
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Form 1449 (Modified) Information Disclosure Statement By Applicant 8 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
	Applicant:	
	John M. de Larios	
	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A8	6,270,584	08/07/2001	Ferrell et al.	134	26
	B8	6,272,712	08/14/2001	Gockel et al.	15	77
	C8					
	D8	6,286,231	09/11/2001	Bergman et al.	34	410
	E8	6,290,780	09/18/2001	Ravkin	134	6
	F8	6,296,715	10/02/2001	Kittle	134	2
	G8	6,319,801	11/20/2001	Wake et al.	438	585
	H8	6,352,082	03/05/2002	Mohindra et al.	134	25.4
	I 8	6,386,956	05/14/2002	Sato et al.	451	57

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J8							
	K8							
	L8							
	M8							
	N8							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O8	
	P8	
	P8	
Examiner		Date Considered

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Form 1449 (Modified) Information Disclosure Statement By Applicant 9 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
	Applicant:	
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	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A9					
	B9	6,401,734	06/01/2002	Morita et al.	134	153
	C9	6,423,148	07/23/2002	Aoki	134	3
	D9	6,439,247	08/27/2002	Kittle	134	102.1
	E9	6,457,199	10/01/2002	Frost et al.	15	77
	F9	6,491,043	12/10/2002	Mohindra et al.	134	25.4
	G9					
	H9	6,493,902	12/17/2002	Lin	15	302
	I 9	6,513,538	02/04/2003	Chung et al.	134	1.2

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J9							
	K9							
	L9							
	M9							
	N9							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O9	
	P9	
	P9	
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Form 1449 (Modified) Information Disclosure Statement By Applicant 10 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
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	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A10	6,51,4921	02/04/2003	Kakizawa	510	175
	B10	6,527,870	03/04/2003	Gotikis	134	6
	C10	6,537,915	03/25/2003	Moore et al.	438	692
	D10	6,532,976	03/18/2003	Huh et al.	134	111
	E10	6,562,726	05/13/2003	Torek et al.	438	745
	F10	6,576,066	06/10/2003	Namatsu	134	30
	G10	6,594,847	07/22/2003	Krusell et al.	15	102
	H10	6,616,772	09/09/2003	de Larios et al.	134	21
	I 10	6,733,596	05/11/2005	Mikhaylichenko et al.	134	6

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J10							
	K10							
	L10							
	M10							
	N10							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O10	
	P10	
	P10	
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Form 1449 (Modified) Information Disclosure Statement By Applicant 11 of 15	Attorney Docket No:	U.S.
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	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A11	6,787,473	09/07/2004	Andreas	438	692
	B11	6,797,071	09/28/2004	Kittle	134	11
	C11	6,802,911	10/12/2004	Lee et al.	134	28
	D11	6,846,380	01/25/2005	Dickinson et al.	156	354.31
	E11	6,851,435	02/08/2005	Mertens et al.	134	99.1
	F11	6,874,516	04/05/2005	Matsuno et al.	134	148
	G11	6,896,826	05/24/2005	Wojtczak et al.	252	79.1
	H11	6,927,176	08/09/2005	Verhaverbeke et al.	438	745
	I 11	6,946,396	09/20/2005	Miyazawa et al.	438	689

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J11							
	K11							
	L11							
	M11							
	N11							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O11	
	P11	
	P11	
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Form 1449 (Modified) Information Disclosure Statement By Applicant 12 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
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	Filing Date:	Group:
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A12	6,951,042	10/04/2005	Mikhaylichenko et al.	15	77
	B12	7,122,126	10/17/2006	Fuentes	216	689
	C12	2002/0072482	06/13/2002	Sachdev et al.	510	175
	D12					
	E12	2002/0121290	09/05/2002	Tang et al.	134	6
	F12	2002/0185164	12/12/2002	Tetsuka et al.	134	148
	G12	2002/0195121	12/26/2002	Kittle	134	3
	H12	2003/0075204	04/24/2003	de Larios et al.	134	21
	I 12	2003/0148903	08/07/2003	Bargaje et al.	510	130

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J12							
	K12							
	L12							
	M12							
	N12							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O12	
	P12	
	P12	
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Form 1449 (Modified) Information Disclosure Statement By Applicant 13 of 15	Attorney Docket No:	U.S.
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A13	2003/0171239	09/11/2003	Patel et al	510	406
	B13	2003/0226577	12/11/2003	Orll et al.	134	1.3
	C13	2004/0002430	01/01/2004	Verhaverbeke	510	175
	D13	2004/0053808	03/18/2004	Raehse et al.	510	447
	E13	2004/0134515	07/15/2004	Castrucci	134	2
	F13	2004/0159335	08/19/2004	Montierth et al.	134	10
	G13	2004/0163681	08/24/2004	Verhaverbeke	134	28
	H13	2004/0261823	12/30/2004	de Larios	134	31
	I 13	2005/0045209	03/03/2005	Tan	134	18

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J13							
	K13							
	L13							
	M13							
	N13							

Other Documents

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	O13	
	P13	
	P13	
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Form 1449 (Modified) Information Disclosure Statement By Applicant 14 of 15	Attorney Docket No:	U.S.
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	Filing Date:	Group:
	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A14	2005/0132515	06/23/2005	Boyd et al.	15	77
	B14	2005/0133060	06/23/2005	de Larios et al.	134	1.3
	C14	2005/0133061	06/23/2005	de Larios et al.	134	6
	D14	2005/0159322	07/21/2005	Min et al.	510	175
	E14	2005/0176606	08/11/2005	Konno et al.	510	175
	F14	2005/0183740	08/25/2005	Fulton et al.	134	3
	G14	2006/0201267	09/14/2006	Liu	74	89.2
	H14	2006/0283486	12/21/2006	de Larios et al.	134	34
	I 14	2006/0285930	12/21/2006	de Larios et al.	406	197

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J14							
	K14							
	L14							
	M14							
	N14							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O14	
	P14	
	P14	
Examiner		Date Considered

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Form 1449 (Modified) Information Disclosure Statement By Applicant 15 of 15	Attorney Docket No:	U.S.
	LAM2P422	10/608,871
	Applicant:	
	John M. de Larios	
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	June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A15	2007/0000518	01/04/2007	Korolik et al.	N/A	N/A
	B15	11/639,752	12/15/2006	Boyd et al.	N/A	N/A
	C15	11/743,283	05/02/2007	Freer et al.	N/A	N/A
	D15					
	E15					
	F15					
	G15					
	H15					
	I15					

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J15							
	K15							
	L15							
	M15							
	N15							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O15	
	P15	
	P15	
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